



## PATENT ABSTRACTS OF JAPAN

(11) Publication number: **2001156055 A**(43) Date of publication of application: **08.06.2001**(51) Int. Cl. **H01L 21/31**

B05B 7/04, C23C 16/448, F17C 7/00, H01L 21/205

(21) Application number: **2000225445**(22) Date of filing: **26.07.2000**(30) Priority: **14.09.1999 JP 11260819**(71) Applicant: **STEC INC**(72) Inventor: **NISHISATO HIROSHI  
MIYAMOTO HIDEAKI****(54) METHOD AND APPARATUS FOR GASIFYING  
LIQUID MATERIAL****(57) Abstract:**

**PROBLEM TO BE SOLVED:** To provide a method and an apparatus for gasifying a liquid material whereby the liquid material can be gasified always with good efficiency and stably.

**SOLUTION:** The liquid material LM and a carrier gas CG are mixed under the flow rate control in a gas-liquid mixing part 39 inside a control valve 1 having a liquid flow rate control function, and resultant gas-liquid mixture M is discharged from a nozzle 42 formed near the flow rate controller 39 to reduce the pressure and gasify the liquid material LM.

COPYRIGHT: (C)2001,JPO

